Special Issue

Advances in Manufacturing, Characterization and Applications of Functional Micro/Nano Structured Surfaces

Message from the Guest Editors

We are pleased to invite you to publish your original research findings in this Special Issue entitled “Advances in Manufacturing, Characterization and Applications of Functional Micro/Nano Structured Surfaces”. This Special Issue aims to seek recent advances in novel and state-of-the-art research and development within the field of advanced manufacturing and characterization technologies of functional micro-/nanostructured surfaces, as well as their applications. In addition, multidisciplinary (physiochemical, micro-/nano- and biomedicine) manufacturing technologies and characterization methods are welcome across all types of papers, such as original research papers and review articles. We look forward to receiving your contributions to the Special Issue.

Guest Editors

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Dr. Nan Zhang

Dr. Wei Hang

Dr. Ruslan Melentiev

Deadline for manuscript submissions

closed (30 April 2024)

Micromachines

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Impact Factor 3.0
CiteScore 6.0
Indexed in PubMed

mdpi.com/si/124922

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Editor-in-Chief

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